

AIOLOS

WAFER LEVEL PRESSURE TEST HANDLER



Aiolos is a wafer level pressure test handler. The correct stimulus is produced by controlling the pressure inside the pressure chamber. High capacity can be achieved with possibility for parallel testing, "on fly" needle cleaning and optional automatic wafer changing.

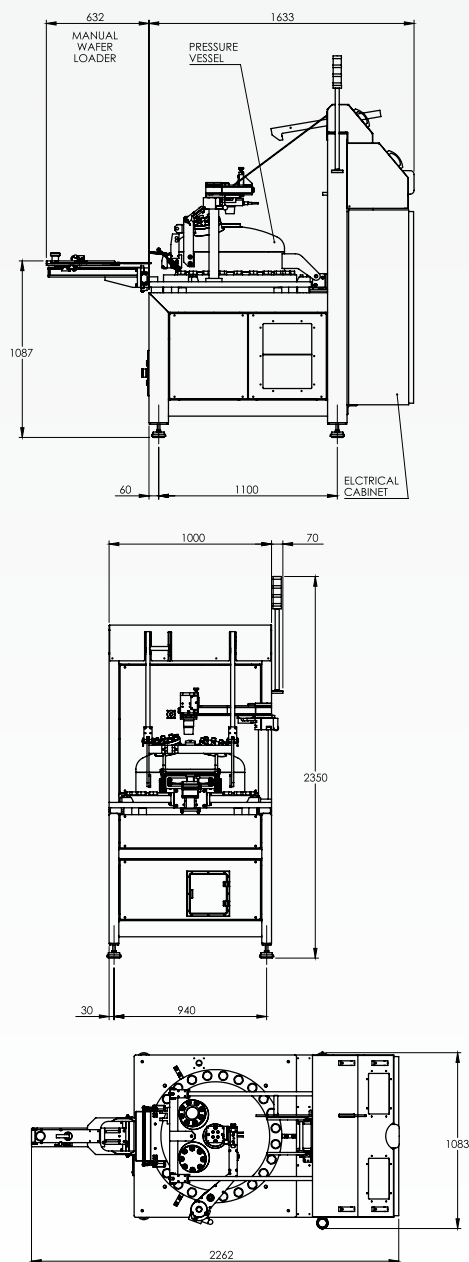
Due to patented intelligent structure of Aiolos, the deformations of the pressure chamber have a minimum impact to the accuracy of the system. Ingenious wafer loading door system enables easy and fast wafer change.

Aiolos has active alignment, which enables best possible testing results, contact positioning and testing of diced wafers. Process related damages to product can be eliminated and quality of the products ensured when testing is done with diced wafer just before packing.

AFORE
Meant for MEMS

AIOLOS

WAFER LEVEL PRESSURE TEST HANDLER



HANDLER MECHANICS

Pressure range	100 – 30 000 mbar (Absolute pressure)
Pressure accuracy	< mbar 50 mbar with coarse control, < 1 mbar with fine control
X-Y-drive accuracy	± 5µm
Z-drive accuracy	± 5µm
Theta correction	Maximum ± 5°
Maximum contact force	10 Kg
Contacting method	Cantilever pins, others by request
Wafer frame size	For 150mm wafers
Index time	<0,5s

CONTROL SYSTEM

User interface	7" colour touch panel and joystick (teach panel)
Communication interface	Ethernet, ASCII-prompt protocol for easy communication with Labview or similar

INFRASTRUCTURE

Weight	1300 Kg
Pressure	6...30 Bar
Vacuum	100 mBar
Power	400 V / 16 A, 3-phase

OPTIONS

Wafer frame ID code reader
Wafer magazine ID code reader
Automatic wafer loading
ESD ionizer
Thermo chuck